

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Hiroki Nakamura *et al.*  
Serial No.: 10/586,400  
Filed: April 20, 2007  
For: VACUUM DEPOSITION METHOD AND SEALED-TYPE EVAPORATION  
SOURCE APPARATUS FOR VACUUM DEPOSITION  
Art Unit: 1712  
Examiner: Keath T. Chen  
Conf. No.: 3841  
Att'y. Docket: 520514.00039

**Response To Species Election Requirement**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

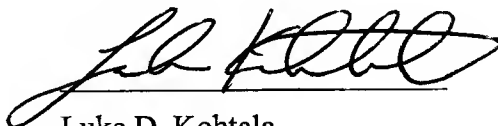
Sir:

In response to the Restriction Requirement mailed June 28, 2010 for the above application, Applicants elect Species IIA shown in Figs. 5-9 for further examination. Claims 9-11 and 13-16 read on the elected species. Claims 9, 10, and 13 are generic to all species in Group II.

No additional fees for filing this response are believed to be due. However, if such fees are due, the Commissioner is hereby authorized to charge them to deposit account no. 17-0055.

Respectfully submitted,

Date: July 28<sup>th</sup>, 2010



Luke D. Kohtala  
Reg. No. 65,536  
Quarles & Brady LLP  
411 East Wisconsin Avenue  
Milwaukee, Wisconsin 53202-4497  
Tel. No. (414) 277-5249